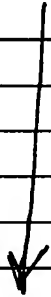
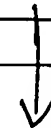


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<u>LIST OF DOCUMENTS CITED BY APPLICANT</u>				Applicant Naomasa Shiraishi et al.			
				Filing Date HEREWITH 1-20-04		Group	
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Examiner Initial		Document Number	Date	Name	Class	Sub-class	Filing Date
AM ↓	AA	3,492,635	1/27/70	Farr	340	15.5	
	AB	3,630,598	12/28/71	Little, Jr.	350	157	
	AC	3,639,039	2/1/72	Rhodes, Jr.	350	162	
	AD	3,658,420	4/25/72	Axelrod	356	71	
	AE	3,729,252	4/24/73	Nelson	350	162	
	AF	3,770,340	11/6/73	Cronin et al.	350	162	
	AG	3,776,633	12/4/73	Frosch et al.	355	132	
	AH	4,132,479	1/2/79	Dubroeucq et al.	355	71	
	AI	4,207,370	6/10/80	Liu	428	204	
	AJ	4,291,938	9/29/81	Wagner	350	91	
	AK	4,472,023	9/18/84	Yamamoto	350	162.11	
	AL	4,739,373	4/19/88	Nishi et al.	355	53	
	AM	4,749,278	6/7/88	van der Werf	356	401	
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Examiner Initial		Document Number	Date	Country	Class	Sub-class	Translation
AM ↓	AN	0 346 844	12/20/89	EPO			
	AO	0 352 975	1/31/90	EPO			
	AP	59-83165	5/14/84	JAPAN			abstract
	AQ	61-41150	2/27/86	JAPAN			abstract
	AR	2-50417	2/20/90	JAPAN			abstract
	AS	2-48090	10/24/90	JAPAN			abstract
OTHER (including author, title, date, pertinent pages, etc.)							
AM ↓	AT	"Extended Focal Depth Optical Microlithography", IBM Technical Disclosure Bulletin, Vol. 32, June 1989, pp 125-127.					
	AU	Delmer L. Fehrs et al., "Illuminator Modification of an Optical Aligner", <u>KTI Microelectronics Seminar</u> , Nov. 6-7, 1989, pp. 217-230.					
	AV	David J. Cronin et al., "Dynamic Coherent Optical System", <u>Optical Engineering</u> , March/April 1973, Vol. 12, pp. 50-55.					
Examiner Alan Mathews				Date Considered 7-6-2005			
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U.S. PATENT DOCUMENTS							
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AM ↓	AA^	4,992,825	2/12/91	Fukuda et al.	355	53	
	AB^	5,004,348	4/2/91	Magome	356	401	
	AC^	5,091,744	2/25/92	Omata	355	53	
	AD^	5,121,160	6/9/92	Sano et al.	355	53	
	AE^	5,153,419	10/6/92	Takahashi	250	201.1	
	AF^	5,191,374	3/2/93	Hazama et al.	355	43	
	AG^	5,208,629	5/4/93	Matsuo et al.	355	53	
	AH^	5,237,367	8/17/93	Kudo	355	67	
	AI^	5,245,384	9/14/93	Mori	355	67	
	AJ^	5,264,898	11/23/93	Kamon et al.	355	67	
	AK^	5,286,963	2/15/94	Torigoe	250	201.2	
	AL^	5,309,198	5/3/94	Nakagawa	355	67	
	AM^	5,329,336	7/12/94	Hirano et al.	355	53	
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AM ↓ ✓	AS^	Naomasa Shiraishi et al., "Optical/Laser Microlithography V", SPIE- The International Society for Optical Engineering, Vol. 1674, March 11-13 1992, pp. 741-752.					
	AT^	George O. Reynolds, "A Concept for a High Resolution Optical Lithographic System for Producing One-Half Micron Linewidths", SPIE, Vol. 633, 1986, pp. 228-238.					
	AU^	A. Szegvári, "On the use of an Illumination azimuth diaphragm during coaxial dark field illumination", January 28, 1923, pp. 1-11.					
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AM 	AA#	5,337,097	8/9/94	Suzuki et al.	353	101	
	AB#	5,392,094	2/21/95	Kudo	355	67	
	AC#	5,440,426	8/8/95	Sandstrom	359	559	
	AD#	5,446,587	8/29/95	Kang et al.	359	562	
	AE#	5,673,102	9/30/97	Suzuki et al.	355	53	
	AF#	Re 34,634	6/7/94	Konno et al.	362	268	
	AG#	5,363,170	11/94	Muraki	355	67	
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AM 	AT#	George Needham, "The Practical Use of The Microscope Including Photomicrography", 1958, pp. 315-327 and 97					
	AU#	John Strong, "Concepts of Classical Optics", 1958, pp. 525-536.					
	AV#	Akira Imai et al., "Lens aberration measurement technique using attenuated phase-shifting mask", Device Development Center, Hitachi Ltd.					
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AM ↓ ↓	AT+	Miyoko Noguchi et al., "Subhalf Micron Lithography System with Phase-Shifting Effect", SPIE, Vol. 1674, 1992, pp. 92-104.					
	AU+	N. Nomura et al., "Heterodyne Holographic Nanometer Alignment for a Wafer Stepper", <u>Microelectronic Engineering</u> 11, 1990, pp. 133-136.					
	AV+	Emi Tamechika et al., "Investigation of single sideband optical lithography using oblique incidence illumination", J. Vac. Sci. Technol. B, Nov/Dec 1992, pp. 3027-3031.					
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AM ↓ ✓	AT*	Keiichiro Tounai et al., "Resolution improvement with annular illumination", VLSI Development Division, NEC Corporation, 1992.					
	AU*	H. Fukuda et al., "Characterization of Super-Resolution Photolithography", <u>IEEE</u> , 1992, pp. 3.2.1 - 3.2.4.					
	AV*	Hiroshi Fukuda et al., "A New Pupil Filter for Annular Illumination in Optical Lithography", <u>Jpn. J. Appl. Phys.</u> , Vol. 31, 1992, pp 4126-4130.					
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AM	AT♦	Maksymilian Pluta, "Principles and Basic Properties" <u>Advanced Light Microscopy</u> , Vol. 1, 1988, pp. 460-463.
	AU♦	H. Wolfgang Zieler, "Physical Optical Aspects of Image Formation", <u>The Optical Performance of the Light Microscope</u> , 1974, pp. 32-55.
V	AV♦	

Examiner

Alan Mathews

Date Considered

7-6-2005

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OTHER (including author, title, date, pertinent pages, etc.)							
AM ↓ ✓	AR☆	James R. Sheats et al., "Optical Lithography Modeling", <u>Microlithography Science and Technology</u> , Chapters 2-4, 1998, pp. 109-271.					
	AS☆	Joseph W. Goodman, "Frequency Analysis of Optical Imaging Systems", <u>Introduction to Fourier Optics</u> , Chapter 6, 1968, pp. 101-197.					
	AT☆	Maksymilian Pluta, "Specialized Methods", <u>Advanced Light Microscopy</u> , Vol. 2, 1989, pp. 100-113.					
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AM 	AT◇	Satoru Asai, et al., "Improving projection lithography image illumination by using sources far from the optical axis", <u>J. Vac. Sci. Technol.</u> , Vol. 9, Nov/Dec 1991, pp. 2788-2791.					
	AU◇	B. J. Lin, "Optical Methods for Fine Line Lithography", <u>Fine Line Lithography</u> , Chapter 2, 1980, pp. 107-232.					
	AV◇						
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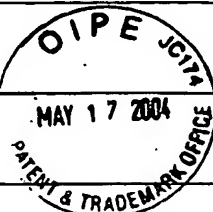
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AM ↓	AA	4,497,015	1/85	Konno et al.	362	268	
	AB	4,952,815	8/90	Nishi	250	548	
	AC	5,307,207	4/94	Ichihara	367	259	
	AD	5,098,184	3/92	vanden Brandt et al.	353	38	
	AE	4,851,978	7/89	Ichihara	355	67	
	AF	5,153,773	10/92	Muraki et al.	362	268	
	AG	4,497,013	1/85	Ohta	362	268	
	AH	4,939,630	7/90	Kikuchi et al.	362	268	
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	AM	WO 92/03842	3/92	WIPO (abstract)			
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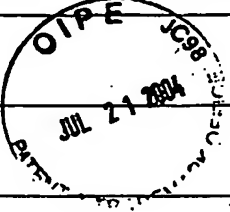
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	AB	5,300,971	4/5/94	Kudo	355	67	
	AC	6,252,647	6/26/01	Shiraishi	355	53	
	AD	6,211,944	4/3/01	Shiraishi	355	53	
	AE	4,619,508	10/28/86	Shibuya et al.	355	67	
	AF	4,769,750	9/6/88	Matsumoto et al.	362	268	
	AG	4,974,919	12/4/90	Muraki et al.	362	268	
	AH	5,016,149	5/14/91	Tanaka	362	268	
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	AM	1,137,243	12/18/68	United Kingdom			
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<i>AM</i>	AA	5,638,211	6/10/97	Shiraishi	359	559	
	AB	4,637,691	1/87	Uehara et al.	359	727	
	AC	4,498,742	2/85	Uehara	359	727	
	AD	4,370,026	1/83	Dubroeuq et al.	355	71	
	AE	4,249,793	2/81	Uehara	359	727	
	AF	4,370,034	1/83	Nohda	351	206	
	AG	4,780,747	10/88	Suzuki et al.	355	68	
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AM	AA	4,566,765	01/28/86	Miyauchi et al.	350	619	
	AB	4,476,519	10/09/84	Hayamizu	362	32	
	AC	4,275,288	06/23/81	Makosch et al.	219	121	
	AD	5,463,497	10/31/95	Muraki et al.	359	618	
	AE	4,241,389	12/23/80	Heimer	362	297	
	AF	4,547,037	10/15/85	Case	350	3.75	
	AG	4,389,701	01/21/83	Phillips	362	308	
	AH	4,585,315	04/29/86	Sincerbox et al.	350	525	
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AM	AL	1-295215	11/28/89	Japan			Abstract
	AM	56-12615	02/07/81	Japan			Abstract
	AN	58-16214	01/29/83	Japan			Abstract
	AO	59-49514	03/22/84	Japan			Abstract
	AP	0 282 593	09/21/88	Europe			
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				Naomasa Shiraishi			
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				U.S. PATENT DOCUMENTS			
Examiner Initial		Document Number	Date	Name	Class	Sub-class	Filing Date
<i>AM</i> ↓	AA	6,233,041	5/15/01	Shiraishi	355	53	
	AB	6,636,293	10/21/03	Shiraishi	355	53	
	AC	6,665,050	12/16/03	Shiraishi	355	53	
	AD	6,704,092	3/9/04	Shiraishi	355	53	
	AE	5,719,704	2/17/98	Shiraishi et al.	359	558	
	AF	6,100,961	8/8/00	Shiraishi et al.	355	67	
	AG	6,377,336	4/23/02	Shiraishi et al.	355	67	
	AH	6,392,740	5/21/02	Shiraishi et al.	355	53	
	AI	6,710,854	3/23/04	Shiraishi et al.	355	67	
	AJ	6,710,855	3/23/04	Shiraishi	355	67	
	AK						
	AL						
AM							
FOREIGN PATENT DOCUMENTS							
Examiner Initial		Document Number	Date	Country	Class	Sub-class	Translation
	AN						
	AO						
	AP						
	AQ						
	AR						
	AS						
OTHER (including author, title, date, pertinent pages, etc.)							
	AT						
	AU						
	AV						
Examiner <i>Alan Mathews</i>				Date Considered <i>7-6-2005</i>			
EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.							